

Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	((determin\$5 or detect\$5 or measur\$5 or inspect\$5 or monitor\$5 or calculat\$5 or identif\$5) near5 (foreign near2 particle) and @ad<=19911017)	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:05
2	BRS	L2	35 (pitch near2 variable) near4 filter	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 09:46
3	BRS	L3	0 1 and 2	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 09:46
4	BRS	L4	2600 pitch near4 filter	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:11
5	BRS	L5	0 1 and 4	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 09:46
6	BRS	L6	9001 spatial near2 filter	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 09:47
7	BRS	L7	9 1 and 6	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 11:42
8	BRS	L8	141 variable near3 (spatial near2 filter)	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 13:22
9	BRS	L9	1779 (((determin\$5 or detect\$5 or measur\$5 or inspect\$5 or identif\$6) near4 (defect\$2 or foreign) with surface) same wafer	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 13:29
10	BRS	L10	3001 (((determin\$5 or detect\$5 or measur\$5 or inspect\$5 or identif\$6) near4 (defect\$2 or foreign) with surface) and semiconductor	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 13:29
11	BRS	L11	0 9 and 8 and @ad<=19911017	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:07
12	BRS	L12	1 10 and 8 and @ad<=19911017	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:07
13	BRS	L13	58 pitch near5 (spatial near2 filter)	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:14
14	BRS	L14	0 1 and 13	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:14
15	BRS	L15	3088 pitch near5 filter	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:14
16	BRS	L16	0 1 and 15	USPAT; US-PPGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/08 14:14